

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 09/298,160  
Filing Date ..... April 22, 1999  
Inventor ..... Dan G. Custer et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1746  
Examiner ..... A. Olsen  
Attorney's Docket No. .... MI22-1172  
Title: Polishing Systems, Methods of Polishing Substrates, and Methods of  
Preparing Liquids for Semiconductor Fabrication Processes

**RESPONSE TO OCTOBER 22, 2001 OFFICE ACTION**

To: Box Non-Fee Amendment  
Assistant Commissioner for Patents  
Washington, D.C. 20231

From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)  
Wells, St. John, Roberts, Gregory & Matkin P.S.  
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Sir:

Responsive to the Office Action dated October 22, 2001, Applicant respectfully requests reconsideration of the above-referenced application in view of the amendments and remarks that follow.

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